



PATENT  
Our Docket: M-CI 4561

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of )  
Ger van den Engh )  
Serial No: 09/847,466 )  
Filed: May 1, 2001 )  
For: APPARATUS FOR DETERMINING )  
RADIATION BEAM ALIGNMENT )

Group Art Unit: 287

Examiner: S. Lee

#7/B  
JPM

Commissioner for Patents  
Washington, D.C. 20231

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Oct. 22, 2002

(date of deposit)

Delbert J. Bacca

Signature

RESPONSE TO OFFICE ACTION

Responsive to the Office Action mailed July 22, 2002, entry  
of the following Amendments and Remarks is respectfully  
requested.

AMENDMENTS

In the specification

Please replace the paragraph starting on page 20, line 28  
and ending on page 21, line 21, with the following paragraph:

*BY*  
An apparatus of the invention can be used to determine  
alignment of a radiation beam emitted from a flow chamber. A  
flow chamber can contain a sample stream in which emission from  
molecules or particles is observed when they pass a point of  
observation. The point of observation can be placed, for  
example, as shown in Figures 2 and 4 as location 4. As shown in  
the Figures, radiation emitted at the point of observation, for  
example, from fluorescent particles that have been contacted with  
radiation of an excitatory wavelength, can be collimated into a  
beam. The beam can be directed toward a screen having a mirrored  
surface interrupted by one or more pin holes such that alignment

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